

REMARKS

This Response, filed in reply to the Office Action dated December 12, 2005, is believed to be fully responsive to each point of rejection raised therein. Accordingly, favorable reconsideration on the merits is respectfully requested.

Claims 1-6 are all the claims pending in the application. Claims 1 and 6 have been rejected under 35 U.S.C. § 103 as being unpatentable over Yamazaki (U.S.P. 6,897,100) in view of Ikeda (U.S.P. 5,183,547). Claims 2-3 have been rejected under Section 103 as being unpatentable over Yamazaki in view of Ikeda and further in view of Chenevas-Paule (previously of record). Claim 4 has been rejected under Section 103 as being unpatentable over Yamazaki in view of Ikeda and further in view of Zhang (previously of record). Claim 5 has been rejected under Section 103 as being unpatentable over Yamazaki in view of Ikeda and Chenevas-Paule and further in view of Zhang. Applicant respectfully submits the following arguments in traversal of the prior art rejections.

The Examiner concedes that Yamazaki does not explicitly teach all features of claim 1, including *inter alia* a vacuum chamber for laser irradiation which has planar dimensions of planar width and a planar length wherein at least one of the length and width is less than twice a respective length or width of a substrate. The Examiner cites Ikeda to make up for this deficiency.

Applicant submits that the Examiner's rejection is improper for at least the following two reasons.

First, Ikeda relates to formation of an optical disc device. By contrast, the claims relate to semiconductor manufacturing. The processes in the optical disc manufacturing are clearly non-analogous art, and as such, the problems pertinent to that field of art would not be pertinent to Applicant's field of invention. Therefore, Ikeda may not be properly applied against the pending claims.

Second, even assuming *arguendo* that Ikeda may be applied against the pending claims, the combination of Yamazaki and Ikeda does not teach each feature of claim 1. Claim 1 describes the relative dimensions of an irradiation chamber in relation to a substrate on which an irradiation system of that chamber operates. In particular, one of the length or width of the chamber is less than twice the width or length of the substrate. Referring to Figs. 1 and 2 of Ikeda, the disc of Ikeda enters through an opening 3, which is slightly larger than the size of the disc to be formed. The chamber dimension is several times larger than the opening 3, which is evident upon examination of Figs. 1 and 2. See also Ikeda col. 6, lines 51-54 and col. 7, lines 46-55. The apparent size reduction in Ikeda relates to use of swinging arms 9, 10. However, the size reduction does not provide a chamber size reduction commensurate with that described by claim 1. Therefore, claim 1 is patentable for at least this reason.

RESPONSE UNDER 37 C.F.R. § 1.111
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The remaining claims are patentable based on their dependency. The additional secondary references of Chenevas-Paule and Zhang do not make up for the deficiencies of the primary combination.

In view of the above, reconsideration and allowance of this application are now believed to be in order, and such actions are hereby solicited. If any points remain in issue which the Examiner feels may be best resolved through a personal or telephone interview, the Examiner is kindly requested to contact the undersigned at the telephone number listed below.

The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account.

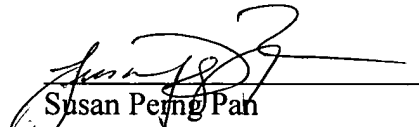
Respectfully submitted,

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